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JUN 28 2004

Applicant(s): Vyvoda et al.

Application No.: 09/776009

Filed: 02/02/2001

Title: Wafer Surface that Facilitates Particle
Removal

Attorney Docket No.: MA-027

Group Art Unit: 2814

Examiner: Anh D. Mai

OFFICIAL

Assistant Commissioner for Patents
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June 28, 2004

REQUEST FOR CONTINUED EXAMINATION

Applicants request continued examination under 37 CFR 1.114. The claim amendments and remarks included herein constitute the required submission. Claims 1-5, 7-14, 30-34, 36-48, and 50-62 have been cancelled in this paper and new claims 63-70 have been added. A complete list of pending claims begins on page 2. Remarks appear on page 3. A Conclusion appears on page 4.

An Information Disclosure Statement is also submitted with this paper.

I hereby certify that this correspondence is being transmitted by facsimile to the U.S. Patent and Trademark Office on the date shown below.

6/28/04
Date
Pamela J. Squyres

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1